

12-27-01

Atty. Docket No. AMAT/5765/CMP/CMP/RKK

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Box Patent Application
Assistant Commissioner of Patents and Trademarks
Washington, D.C., 20231

12/20/01
JC931 U.S. PTO
10/026854

Re: Inventor(s): Shijian Li; Liang-Yuh Chen; and Alain Duboust
Title: ARTICLES FOR POLISHING SEMICONDUCTOR SUBSTRATES

Transmitted herewith is the patent application identified above, including:

- ☒ Specification, claims and abstract, totaling 27 pages.
- ☒ Drawings totaling 9 pages, ☒ Formal ☐ Informal.
- ☒ Executed Declaration and Power of Attorney.
- ☐ Information Disclosure Statement w/ Form 1449 and References.
- ☒ Assignment of the invention to **Applied Materials, Inc.**
- ☒ Assignment Recordation Cover Sheet

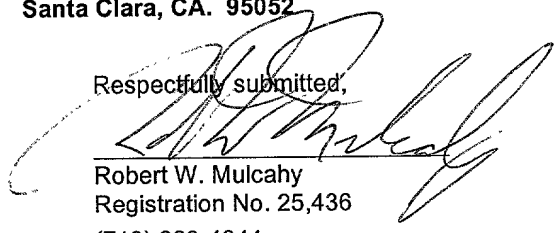
FEE CALCULATION					
Fee Items	Claims Filed	Included With Basic Fee	Extra Claims	Fee Rate	Total
Total Claims	38	-20=	18	x \$18.00	\$324.00
Independent Claims	3	-3=	0	x \$84.00	\$0.00
Basic Filing Fee				\$740.00	\$740.00
TOTAL FEES					\$1,064.00

- ☒ The Commissioner is hereby authorized to charge **\$1,064.00** to Deposit Account No. 50-1074/AMAT/5765/CMP/CMP/RKK.
- ☒ The Commissioner is hereby authorized to charge any additional fees which may be required, or credit any overpayment to Deposit Account No. 50-1074/AMAT/5765/CMP/CMP/RKK. A duplicate copy of this transmittal is enclosed.
- ☒ Please address all future correspondence to:

**PATENT COUNSEL
APPLIED MATERIALS, INC.
Legal Affairs Department
P.O. BOX 450A
Santa Clara, CA. 95052**

I hereby certify that this correspondence is being deposited with the United States Postal Service as express mail in an envelope addressed to: Commissioner of Patents and Trademarks, Washington, D.C. 20231.

Respectfully submitted,


Robert W. Mulcahy
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Express Mail Receipt No.: EV 041915785

Date of Deposit: 12-20-01

Signature: 